

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

Page 1 of 2	Application Number	10/700,279
	Filing Date	November 3, 2003
	First Named Inventor	Jun Yan
	Group Art Unit	To be Assigned
	Examiner Name	To be assigned
	Attorney Docket Number	MVIS 02-24

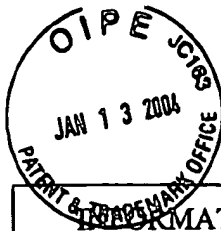
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	
Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
WJ	CONANT, NEE, LAU and MULLER, "A Fast Flat Scanning Micromirror," 2000 Solid-State Sensor and Actuator Workshop, Hilton Head, SC, June 2000, pp.6-9
WJ	CONANT, NEE, LAU and MULLER, "Dynamic Deformation of Scanning Micromirrors," presented at IEEE/LEOS Optical MEMS 2000, Kauai, Hawaii, August 2000

Examiner Signature		Date Considered	6/10/05
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